

Precision Engineering within the National Ignition Campaign

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Precision Engineering within the National Ignition Campaign



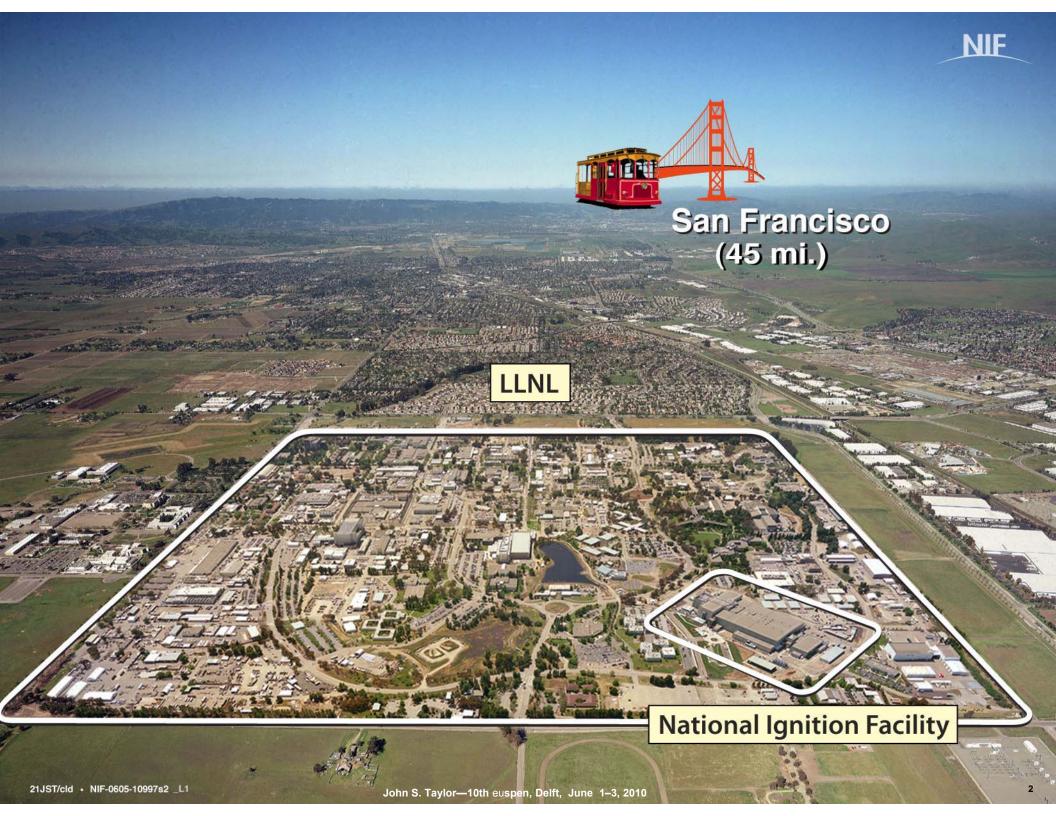
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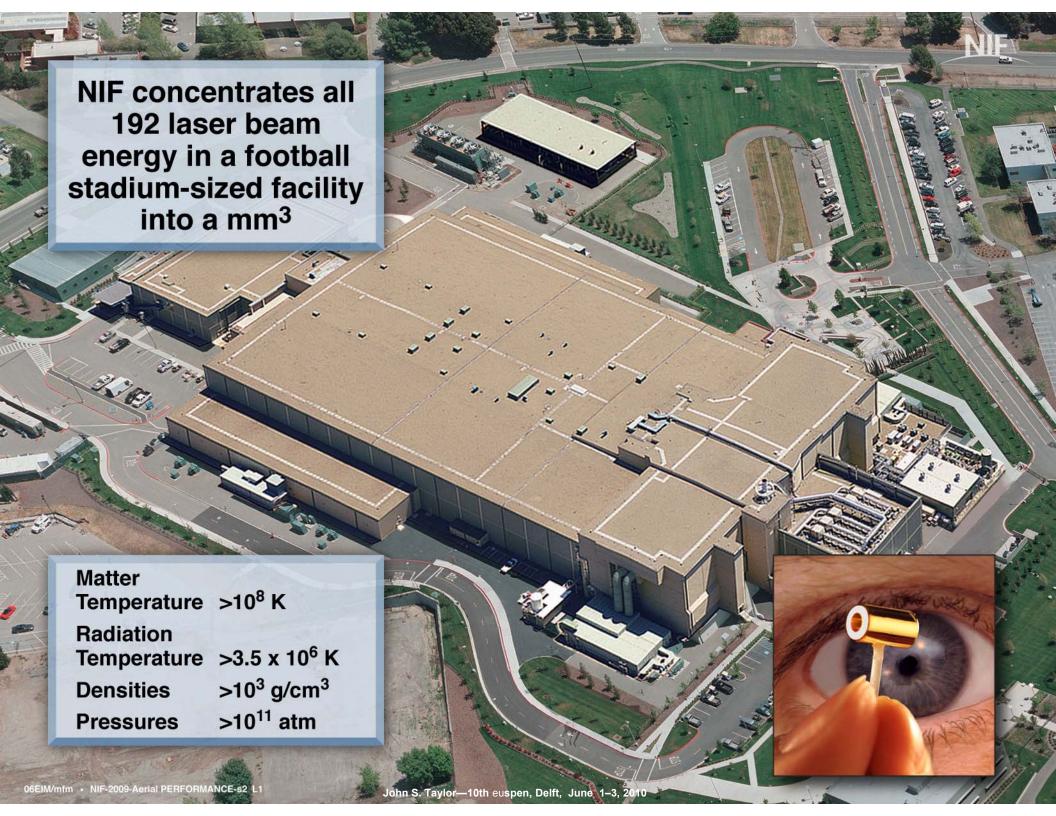
The 10th International Conference of the European Society for Precision Engineering and Nanotechnology Delft, the Netherlands

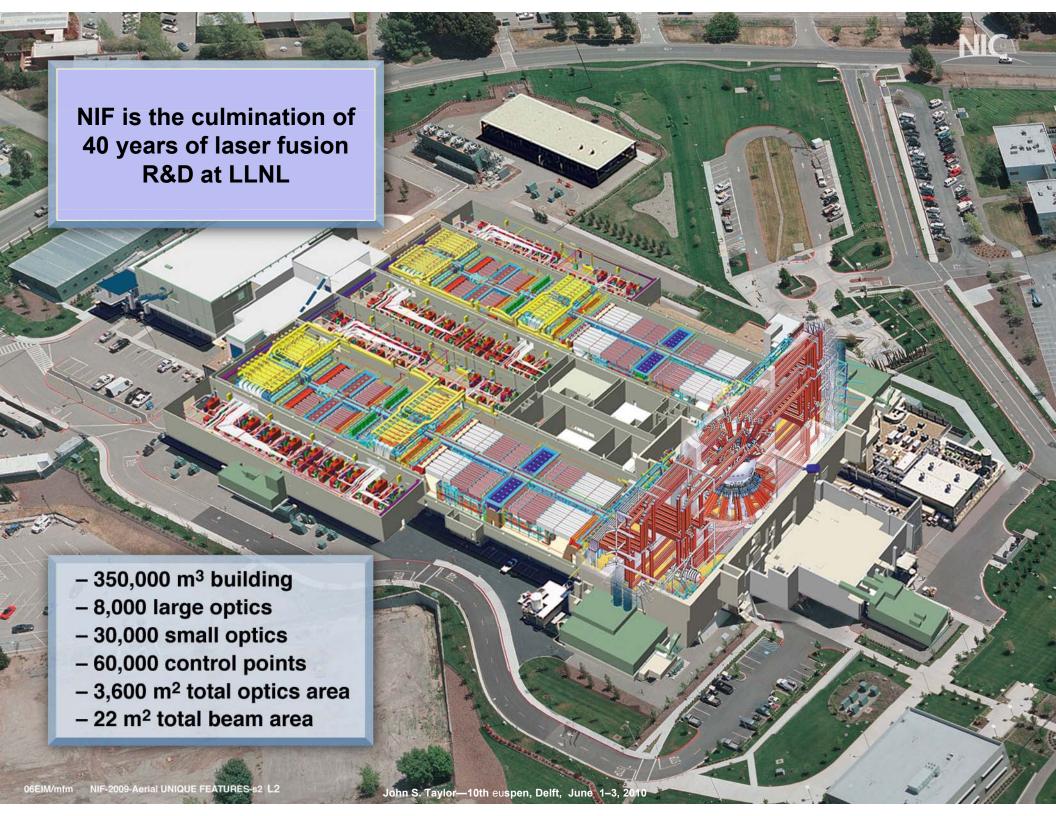
June 1-3, 2010 This work performed under the auspices of the U.S. Department of Energy by Lawrence Livermore National Laboratory under Contract DE-AC52-07NA27344

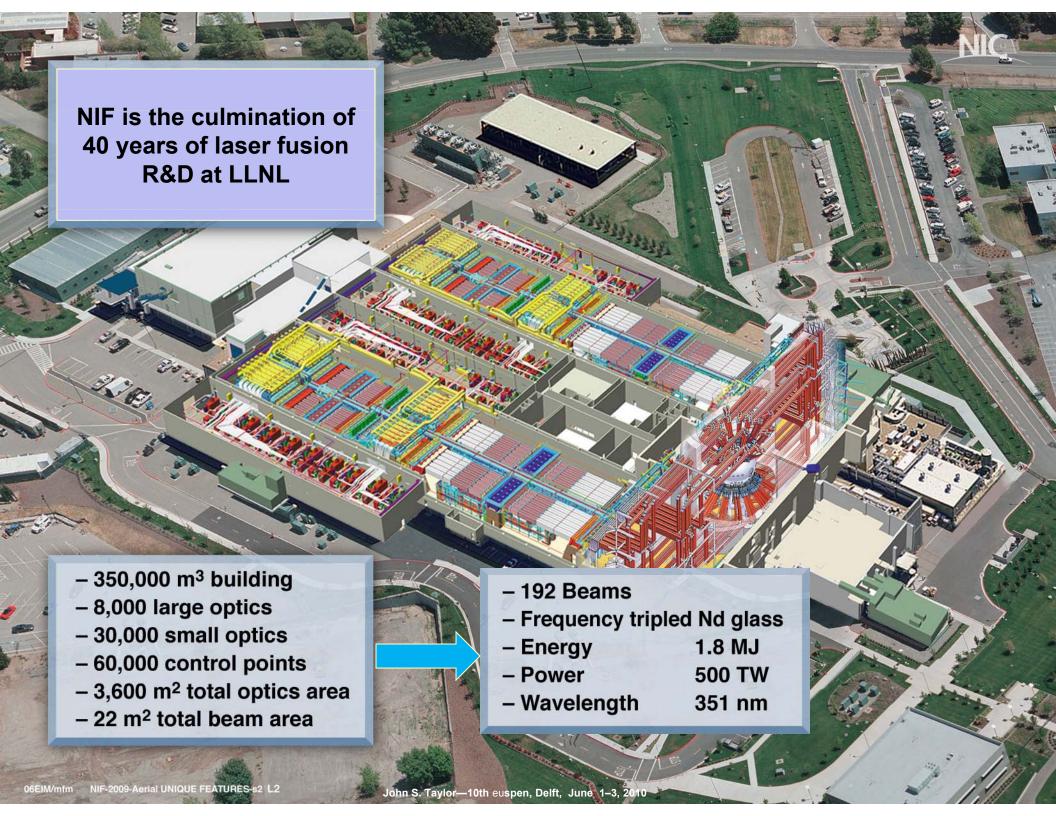
Ted Saito

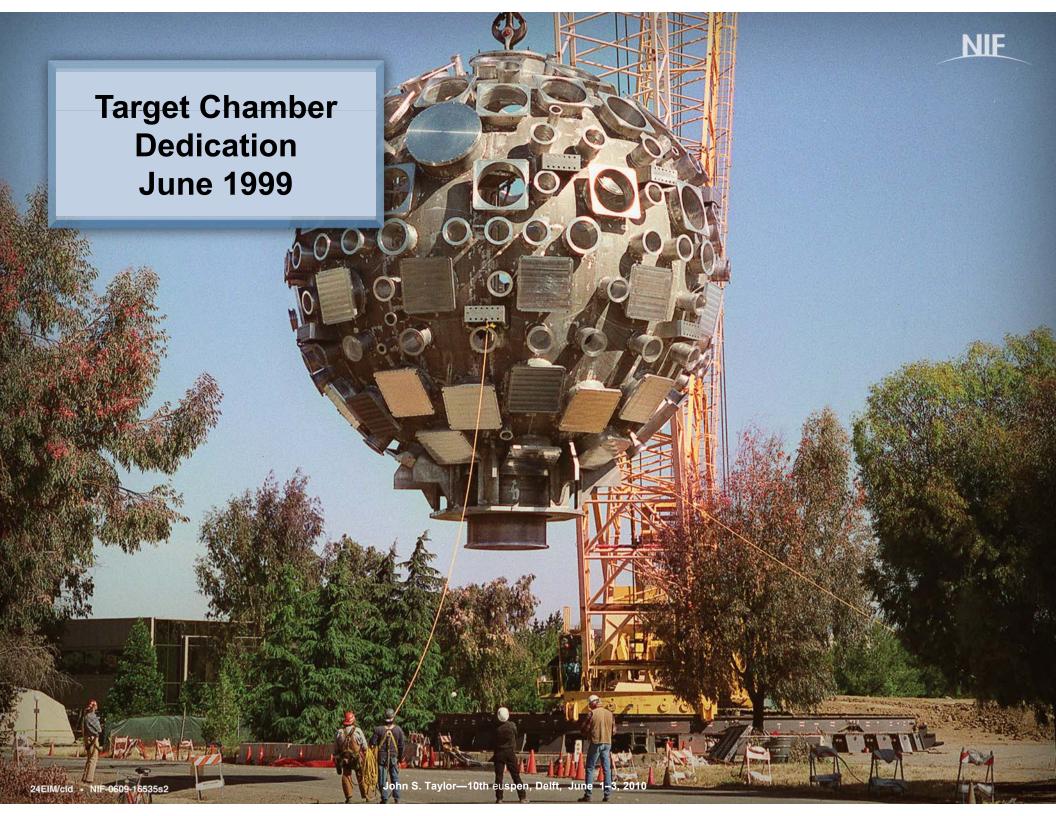
Richard Montesanti



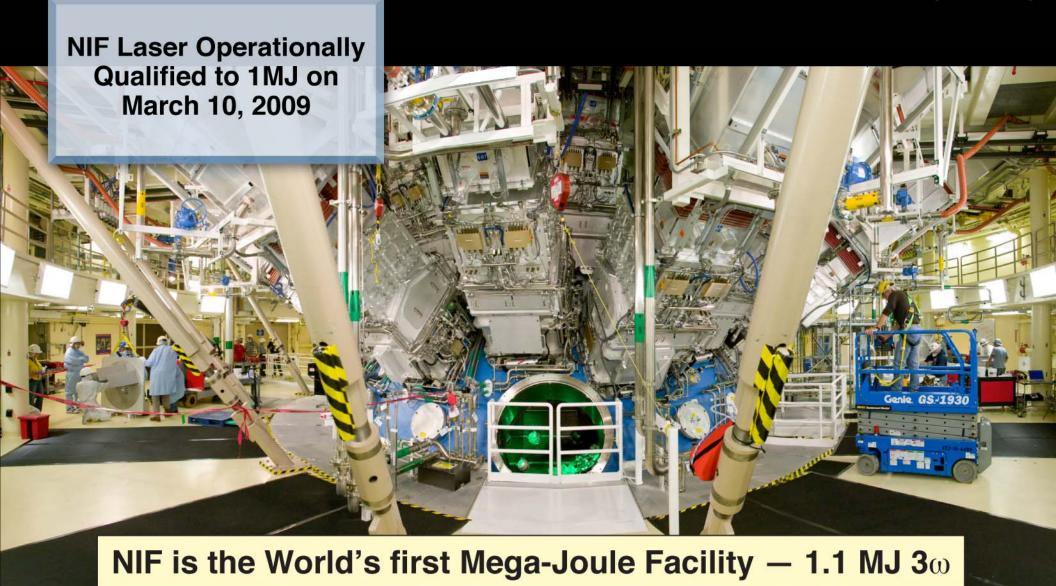








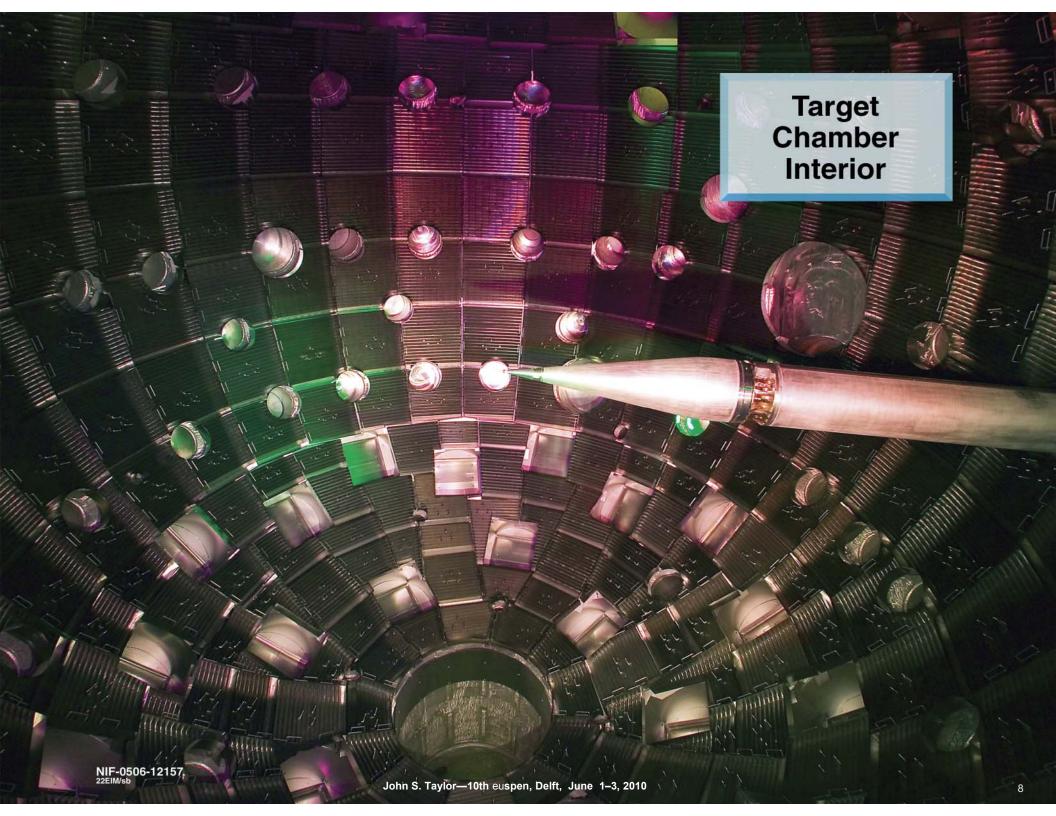


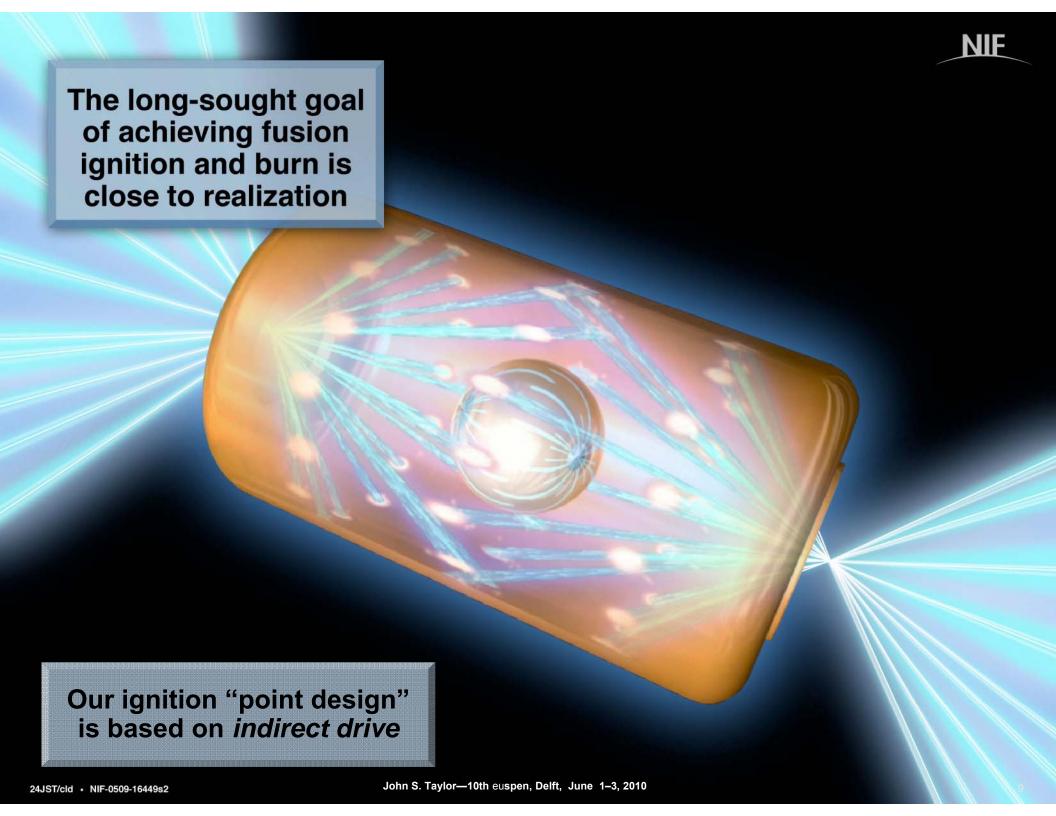




Cluster 2

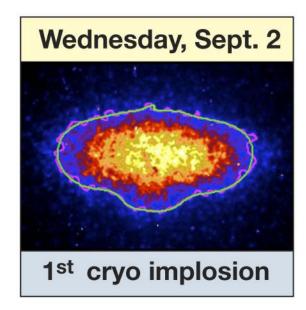
Cluster 1

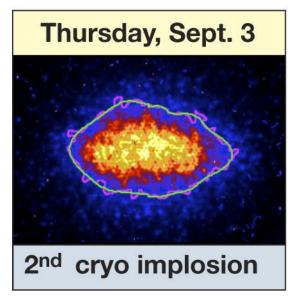


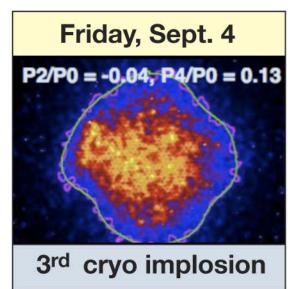


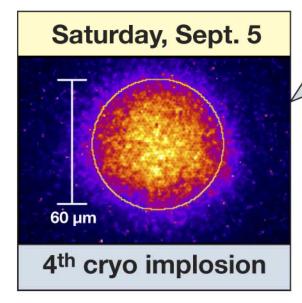


Capsule implosions in cryogenic gas-filled hohlraums have shown good symmetry at 270 eV





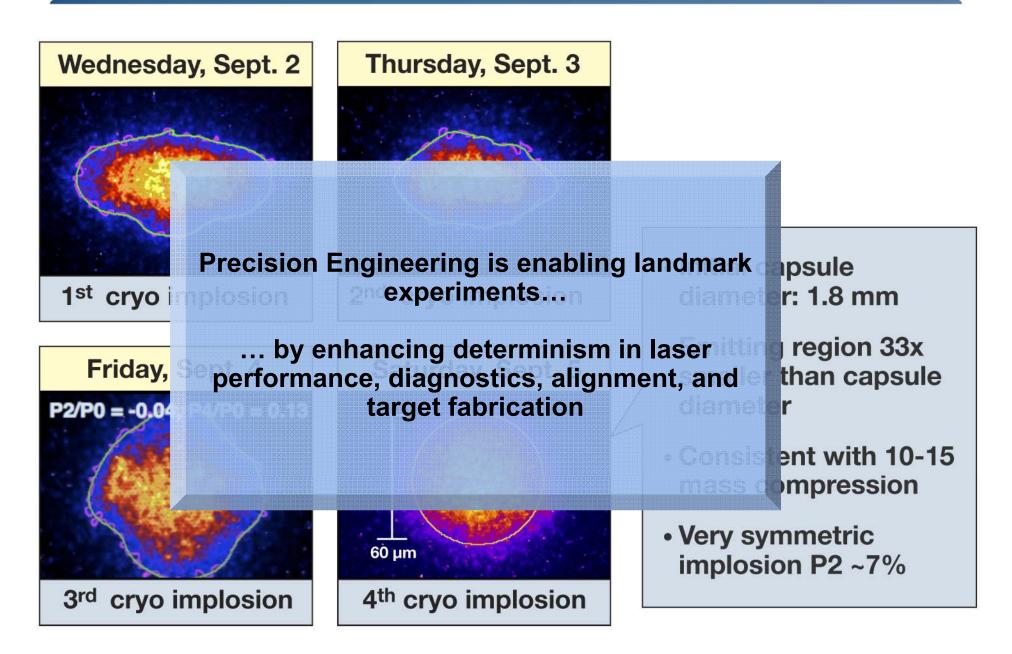




- Initial capsule diameter: 1.8 mm
- Emitting region 33x smaller than capsule diameter
- Consistent with 10-15 mass compression
- Very symmetric implosion P2 ~7%



Capsule implosions in cryogenic gas-filled hohlraums have shown good symmetry at 270 eV



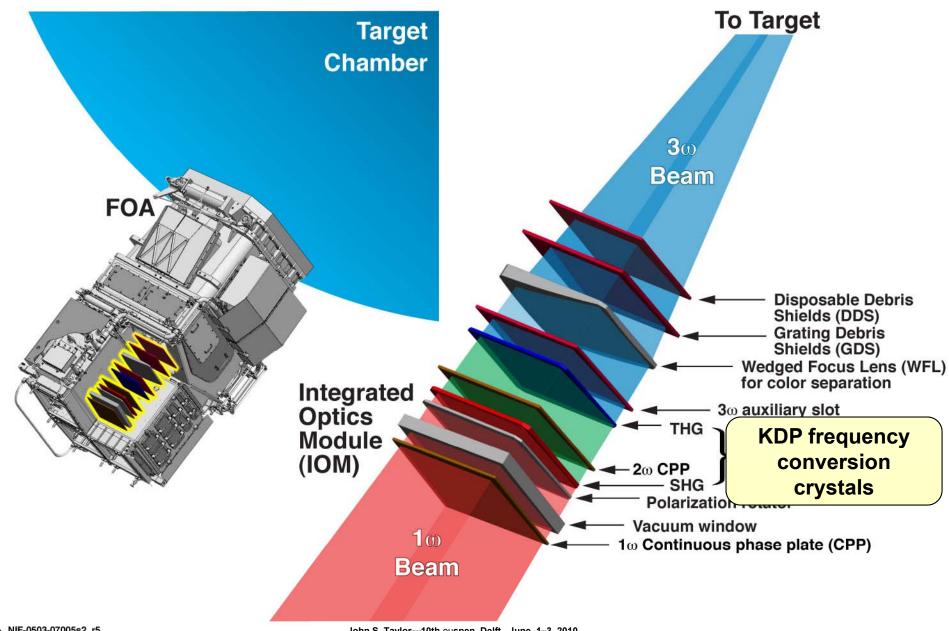


In this very brief talk, we'll discuss how precision engineering impacts 4 key areas of NIF

- Diamond turning of KDP crystals
- Mitigation of laser damage on optics
- Alignment of lasers, targets, diagnostics
- Target fabrication

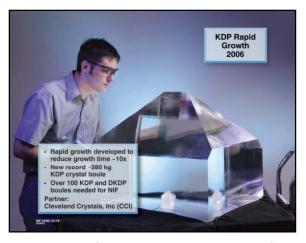


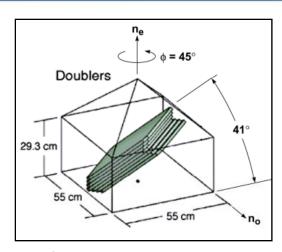
The Final Optics Assembly (FOA) combines a number of critical functions into a single compact package





KDP Semi Finishing Machine – Vertical Axis Fly-cutter



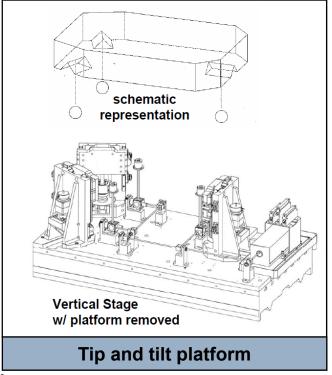


- KDP Optics are used for laser frequency conversion
- NIF operates by first doubling and then tripling
- Crystal growth axis determines frequency

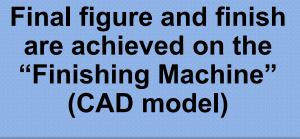




Diamond Fly-cutting to obtain the required crystal angle







Workslide motions sensitive direction:

Straightness (horizontal) < 100nm/500mm

Repeatability < 50nm

Fly-cutter (@ 1000rpm)

Asynchronous error motion < 12nm

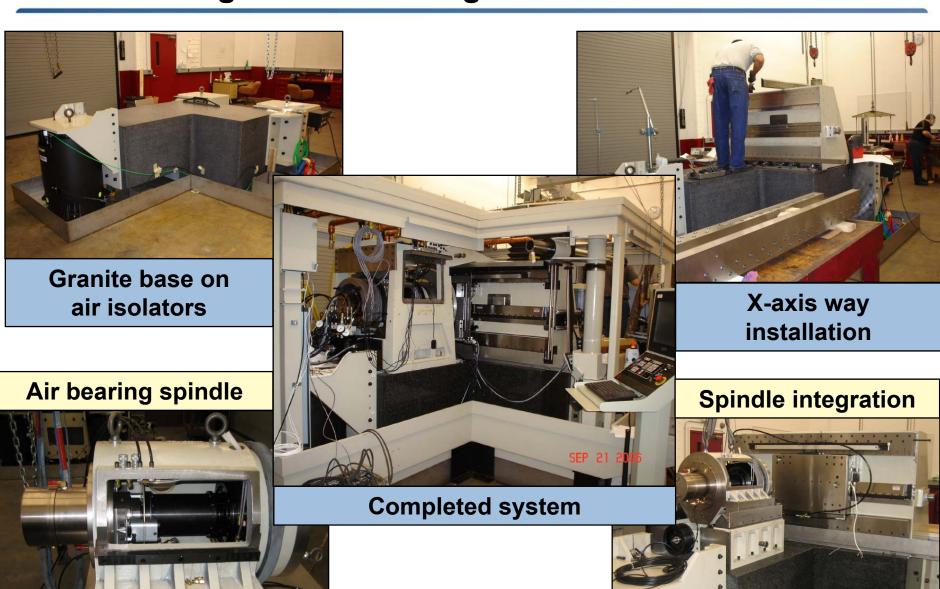
Thermal growth < 10nm/hr

Fly-cutter carriage motion

Slide Pitch < 0.5 arcsec Slide Yaw < 0.2 arcsec



KDP Finishing Machine during the build



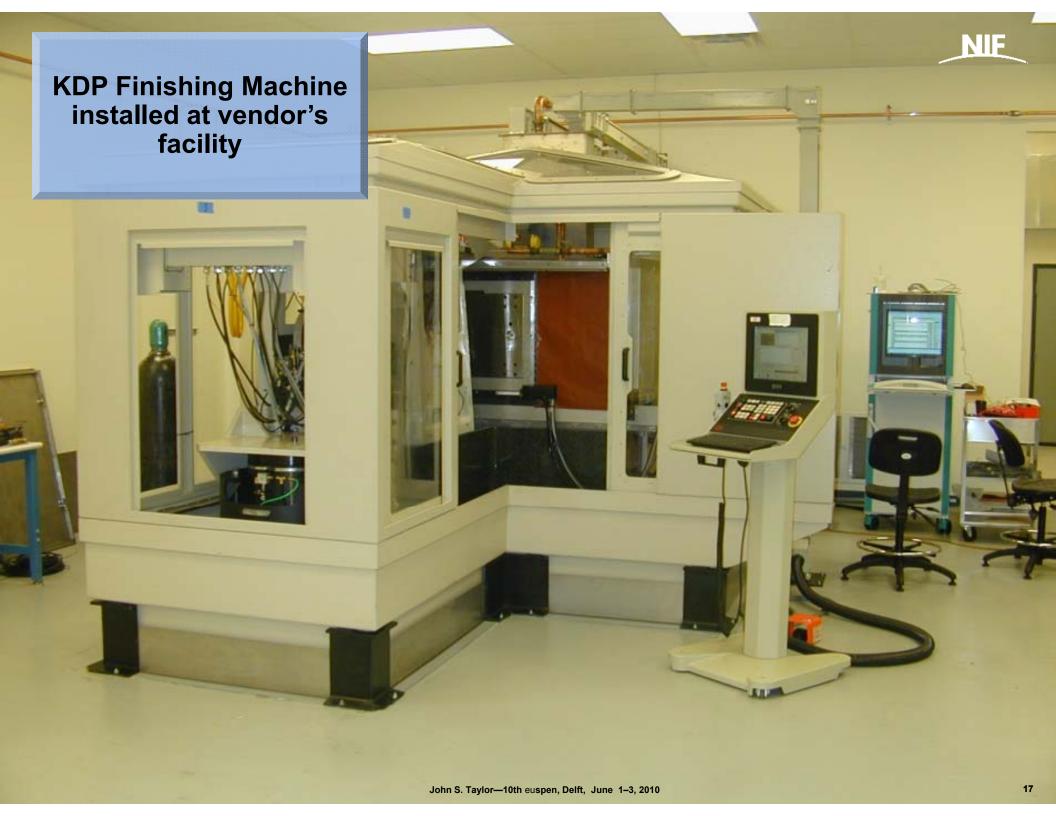
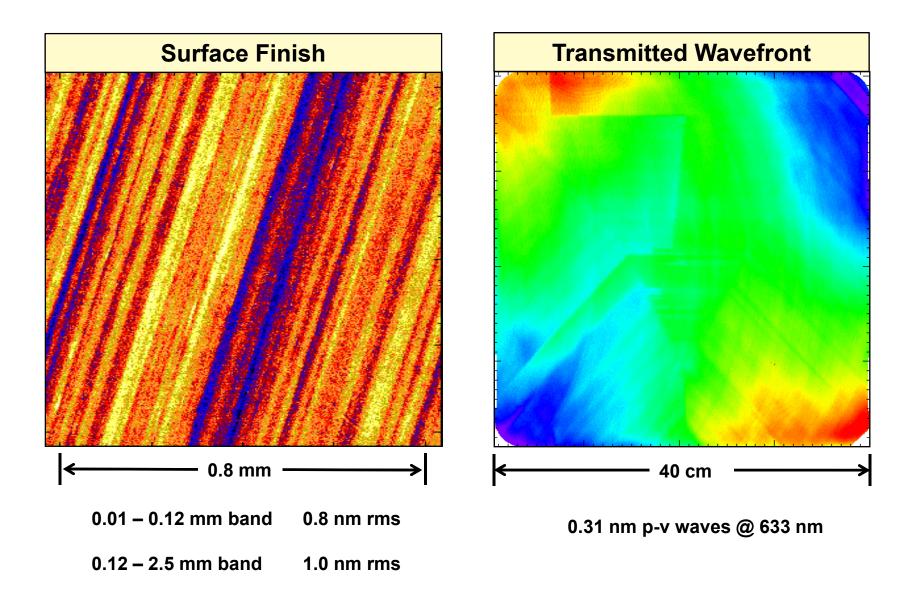


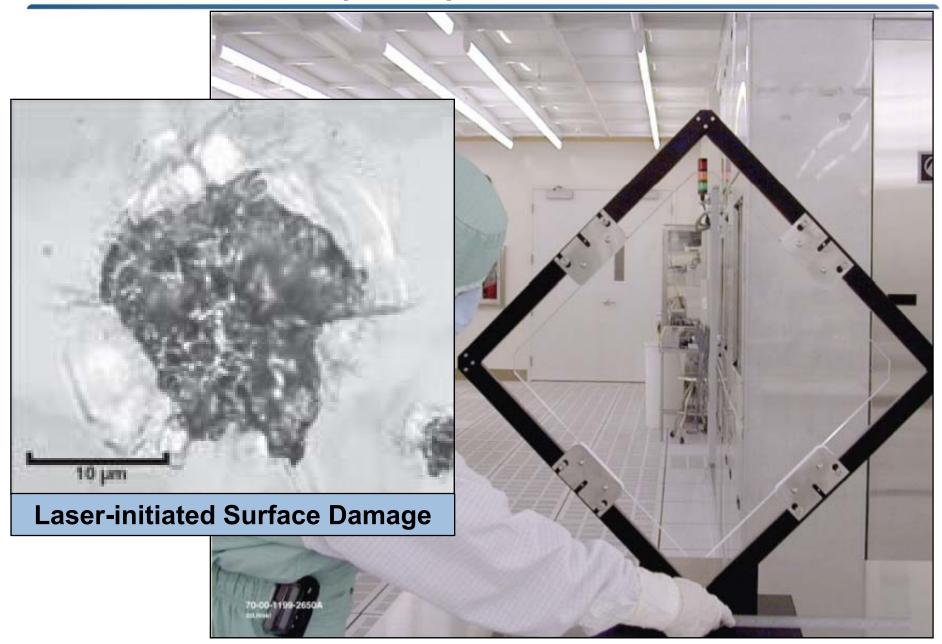


Figure and finish achieved by the final finishing machine meet NIF specifications





KDP frequency conversion crystals are about 1 cm thick with a 40 cm square aperture





The KDP crystal is positioned above the milling spindle and machining stages

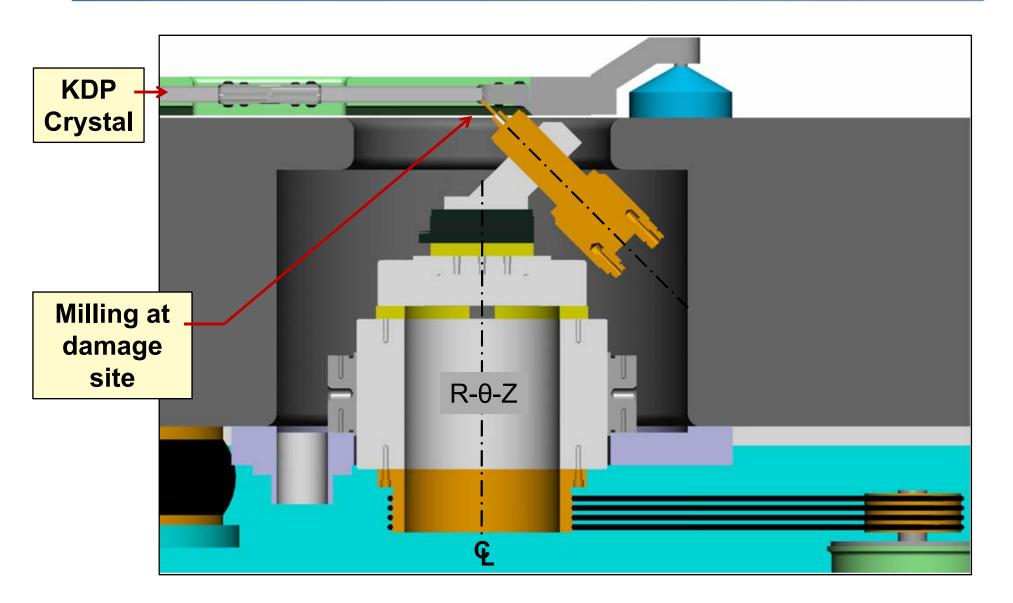
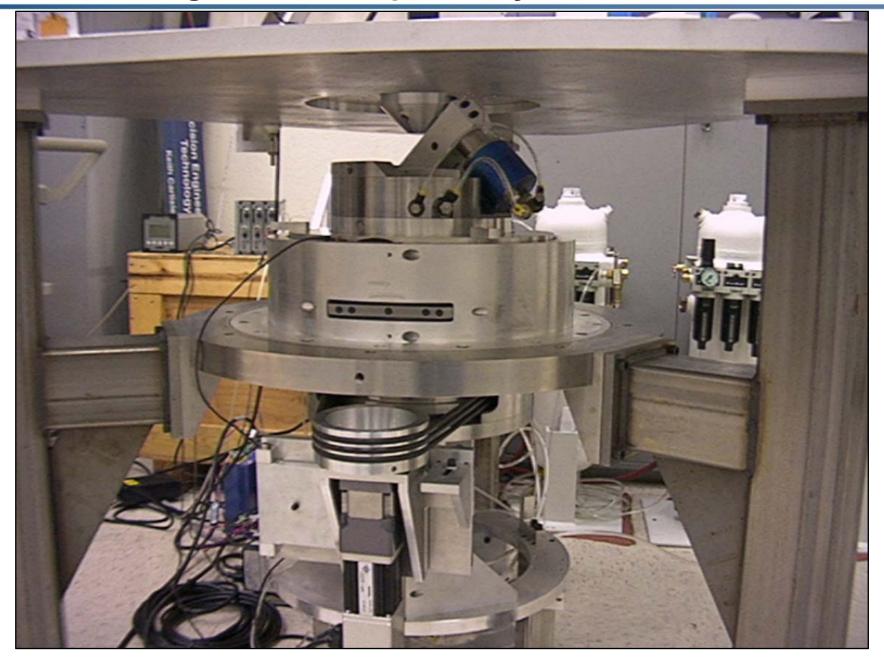




Photo of mitigation development system





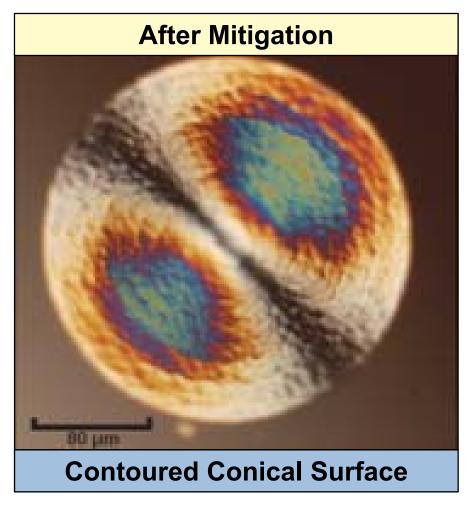
Full-scale KDP mitigation tool





Example of KDP damage site mitigated by diamond milling operation







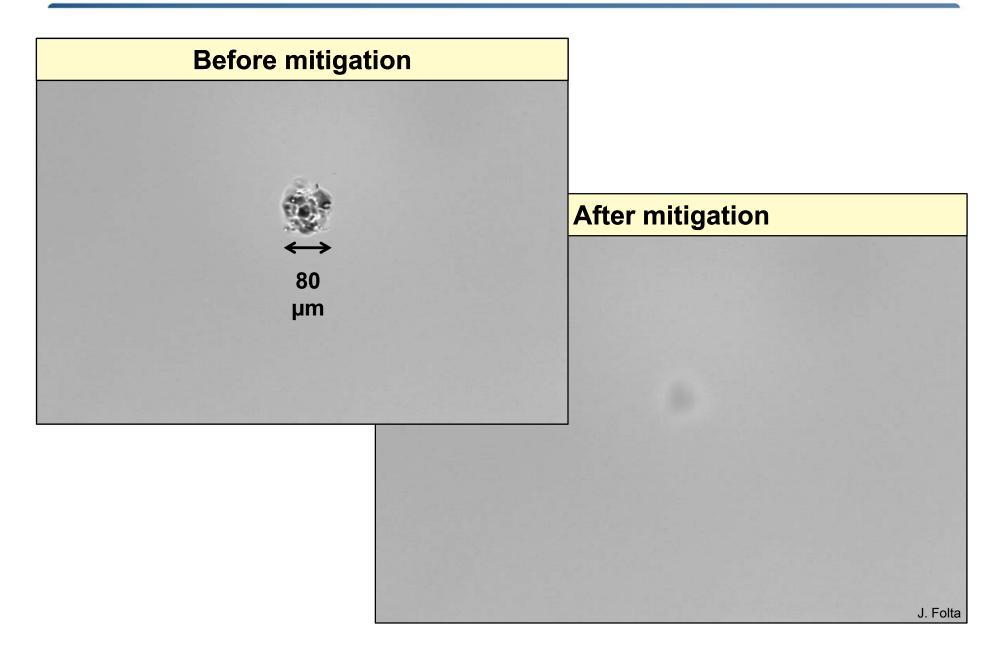


We have engineered machines and facilities to perform production mitigation on NIF optics



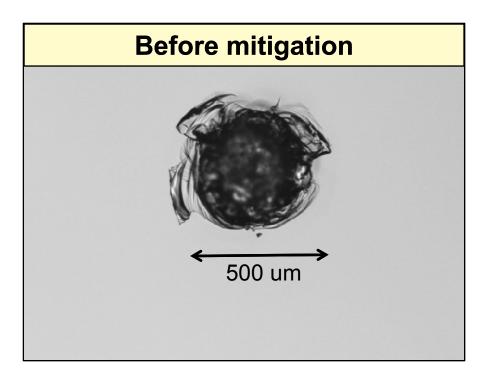


A collimated CO₂ laser beam is used to mitigate small damage sites on large optics instead of refinishing them



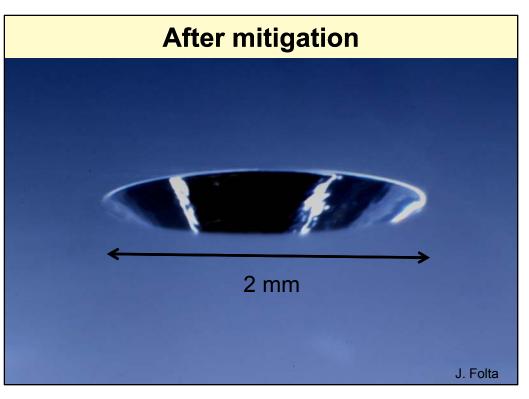


A focused CO₂ laser can be used to ablate conical pits to mitigate damage sites as large as 500 µm



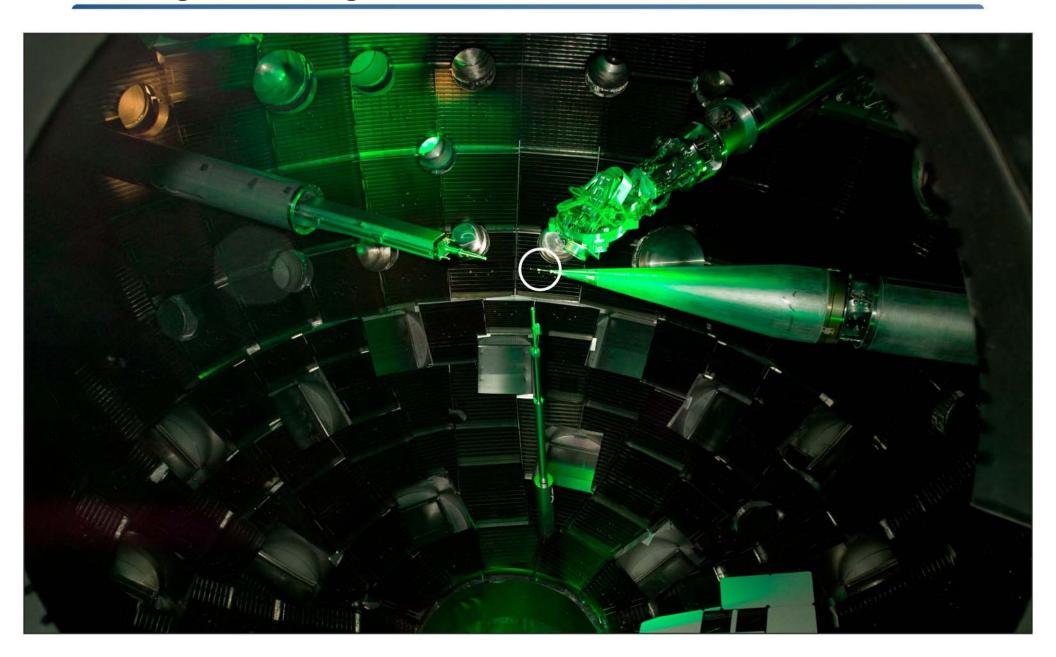
Rapid scanning of tightly-focused high-power CO₂ laser pulses to remove flaws

- Precise shape control
- Fairly wide process margin
- Scalable
- Damage robust



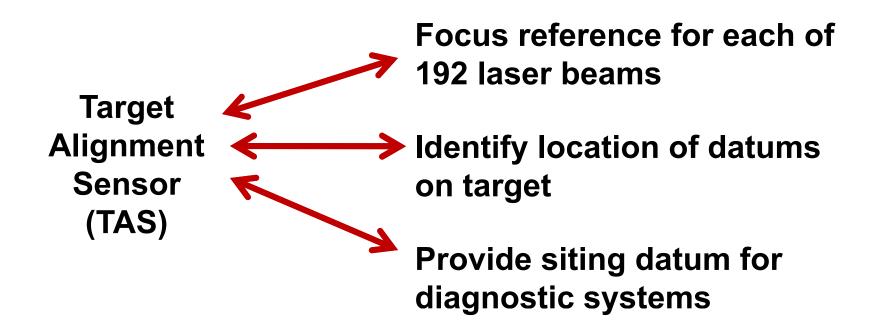


How do we go about aligning 192 laser beams, the target and diagnostics?





Target Alignment Sensor (TAS)

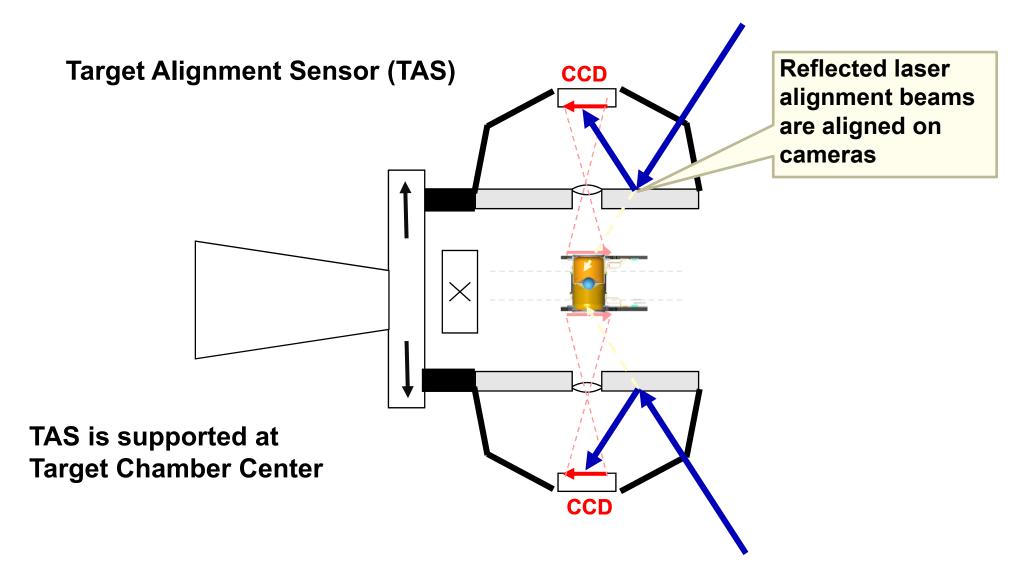


TAS links the coordinates of the key elements of a NIF experiment



192 beams are aligned to the upper and lower cameras with an automated tool

Beams are aligned to a setpoint on the upper and lower CCDs

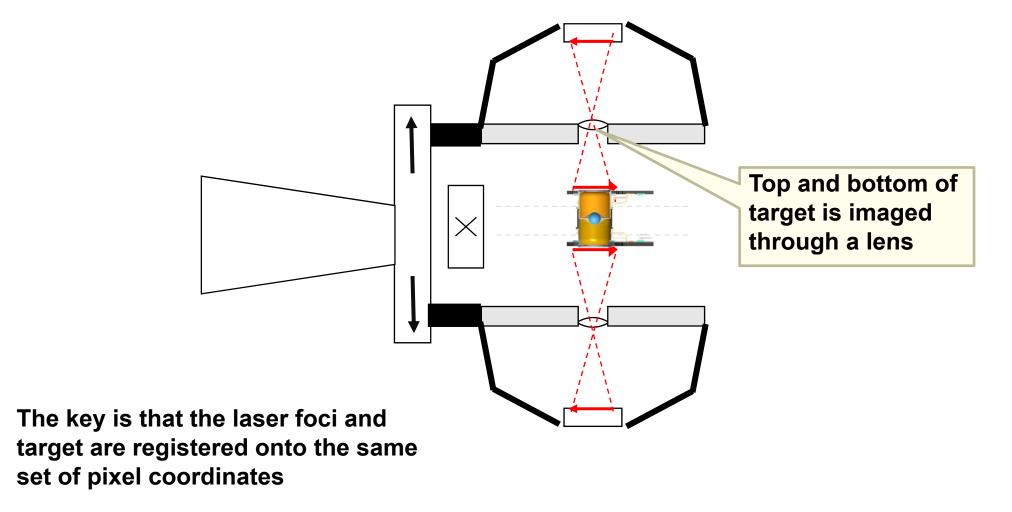




Target is aligned to a setpoint on the upper and lower CCD cameras

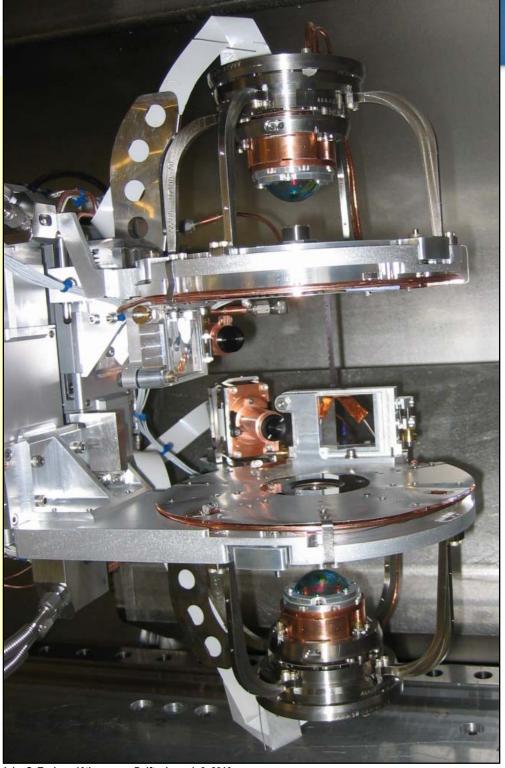
Platens open to focus and align target.

- Upper and lower cameras set four degrees of freedom
- Two side camera set target height





- Target alignment sensor has been successfully deployed on NIF shots over one year
 - TAS is an intermediary between beams and targets
 - Calibrated accuracy of TAS is the central component of beamto-target error budget
 - Requalification is expensive so stability is important



John S. Taylor—10th euspen, Delft, June 1-3, 2010



Alignment performance

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Target to NIF coordinate origin (1 mm zonal position req't): 300 µm deviation at last survey
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Target-to-chamber shot-to-shot position repeatability: <100 µm

Position of 96 beam centroid at hohlraum:

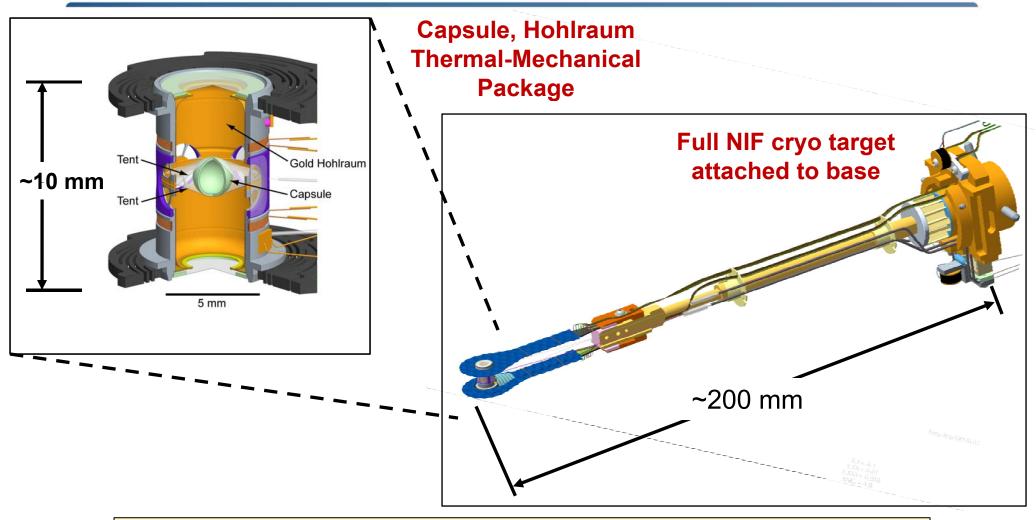
<25 µm

Beam pointing to target (1-σ of 96 beams): 64 μm rms

Diagnostic line of sight alignment (2-σ): <500 μm



Fabricating and measuring targets is a fertile area for exercising precision engineering concepts



Component tolerances: 1-3 μm

Assembly tolerances: 1-20 μm Dynamic Range: 1:10⁴

Bond gap tolerances: 0.25 μm



Fabricating and measuring targets is a fertile area for exercising precision engineering concepts



The dynamic range of 1:10⁴ is challenging:

Agility

~10 mm

required for new target types, target design modifications, and component variances

Human interface for integrating motion control, force, visible-

light microscopy, bonding

Production rate

greater than prototyping, less than HVM

Size

precludes use of many traditional tools

(indicators, fasteners, etc)

Component tolerances: 1-3 µm

Assembly tolerances: 1-20 μm

Bond gap tolerances: ~0.25 µm

Dynamic Range: 1:10⁴



Examples of Precision Engineering concepts in target fabrication

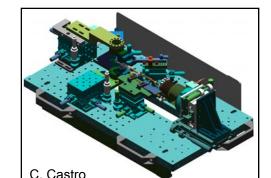
Precision Concept

Example

- Rigorous tolerance analysis
 - Monte Carlo analysis

Hohlraum length

- Controlled degrees of freedom
- Precision with agility



Flex-FAM

Rick Montesanti will discuss precision assembly in his talk

Final Assembly Machine

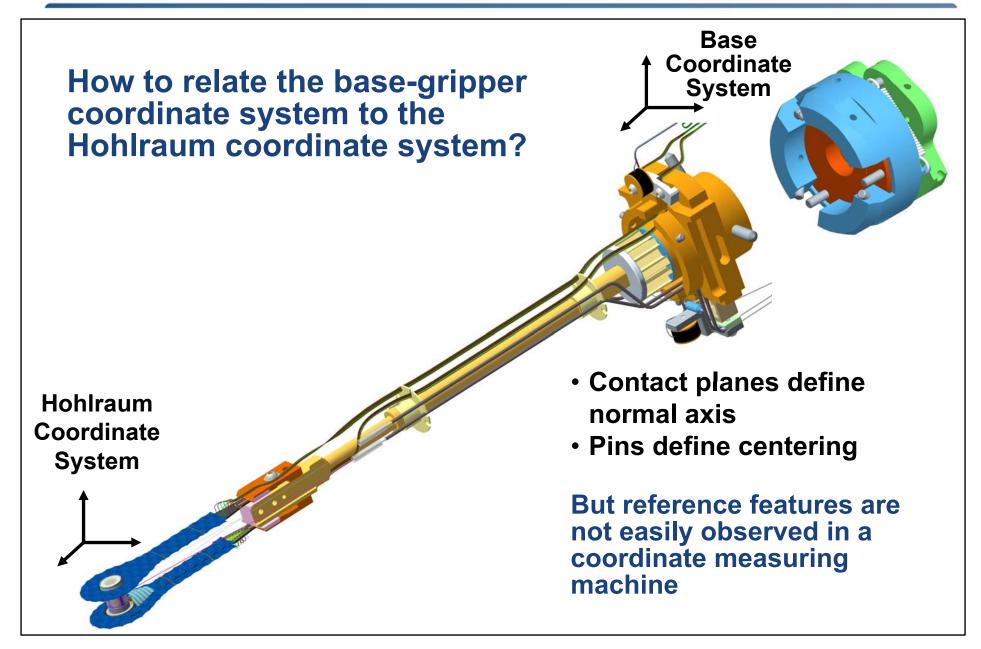


Design for measurability

Base metrology features



Design for Measurability





The design of metrology features onto the base enabled datums to be defined to register the Hohlraum

